

VNF-200 近场特性分析仪

VNF-200 near-field characteristic analyzer

- 远方VNF-200 VCSEL近场特性分析仪专为VCSEL的表面近场特性分析设计，兼具测量速度快、光学分辨率高、测量精度高的特征。仪器采用显微光学系统与成像系统结合的方式，并依据VCSEL的特性优化设计，实现VCSEL的高倍率显微成像辐射分析。通过单次测量得到VCSEL表面二维阵列排布、坏点检测及辐亮度数据，同时得到单点尺寸。配备专用分析软件，可输出符合标准的测试报告。适用于产线及实验室中VCSEL表面特性的快速、精确分析。

The remote VNF-200 VCSEL near-field characteristic analyzer is specially designed for the surface near-field characteristic analysis of VCSEL. It features fast measurement speed, high optical resolution and high measurement accuracy. The instrument combines the micro optical system with the imaging system, and optimizes the design according to the characteristics of VCSEL to achieve the high magnification microscopic imaging radiation analysis of VCSEL. The two-dimensional array arrangement, bad spot detection and radiance data of VCSEL surface are obtained through a single measurement, and the single point size is also obtained. Equipped with special analysis software, it can output test reports that meet the standards. It is suitable for rapid and accurate analysis of VCSEL surface characteristics in production lines and laboratories.



技术参数 Specifications

- 1) 传感器: 800万像素
1) Sensor: 8 megapixel
- 2) 光谱范围: 400 ~ 1000 nm
2) Spectral range: 400~1000 nm
- 3) 视场: 2×2 mm
3) Field of view: 2 × 2 mm
- 4) 分辨率: 1×1 μm
4) Resolution: 1 × one μ m